

Substitute for form 1449A/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)			<b>Complete if Known</b>	
			Application Number	Not Yet Assigned 10/719177
			Filing Date	Herewith
			First Named Inventor	Miller, David
			Art Unit	Not Yet Assigned 2834
Examiner Name	Not Yet Assigned T. Dougherty			
Sheet 1	of 3	Attorney Docket Number		019930-002840

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number Kind Code <sup>2</sup> (if known)			
mb	AA	5,414,540	05/09/95	Patel et al.	
mb	AB	5,917,625	06/29/99	Ogusu et al.	
mb	AC	5,999,672	12/07/99	Hunter et al.	
mb	AD	6,028,689	02/22/00	Michalick et al.	
mb	AE	6,040,935	03/21/00	Michalick	
mb	AF	6,097,859	08/01/00	Solgaard	
mb	AG	6,108,471	08/22/00	Zhang et al.	
mb	AH	6,128,122	10/03/00	Drake et al.	
mb	AI	09/442,061	11/16/99	Weverka, et al.	
	AJ	US-			
	AK	US-			
	AL	US-			
	AM	US-			
	AN	US-			
	AO	US-			
	AP	US-			
	AQ	US-			
	AR	US-			
	AS	US-			
	AT	US-			

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Country Code <sup>3</sup>	Number <sup>4</sup>	Kind Code <sup>5</sup> (if known)		
	AU					<input type="checkbox"/>
	AV					<input type="checkbox"/>
	AW					<input type="checkbox"/>
	AX					<input type="checkbox"/>
	AY					<input type="checkbox"/>
	AZ					<input type="checkbox"/>
	BA					<input type="checkbox"/>
	BB					<input type="checkbox"/>

Examiner Signature	<i>Thomas M. Dougherty</i>	Date Considered	3-2-05
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			Examiner Name	Not Yet Assigned <u>T. Dougherty</u>	
Sheet	<u>2</u>	of	<u>3</u>	Attorney Docket Number	019930-002840

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
<u>tmk</u>	BC	T. Akiyama, et al., "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993; pp. 106-110	
<u>mm</u>	BD	Kenneth Bean, et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. Ed-25, No. 10, October 1978	
<u>mm</u>	BE	Dino R. Ciarlo, "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992	
<u>mm</u>	BF	A.S. Dewa, et al., "Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96	
<u>mm</u>	BG	Joseph Ford et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999	
<u>mm</u>	BH	J. Grade et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100	
<u>mm</u>	BI	V. Kaajakari et al., "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000); pp. 60-65	
<u>mm</u>	BJ	T.L. Koch et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J.App. Phys. 62 (8), 15 October 1987	
<u>mm</u>	BK	I. Nishi et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 <sup>th</sup> May 1985	
<u>mm</u>	BL	P. Phillippe et al., "Wavelength demultiplexer: using echelette gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985	
<u>mm</u>	BM	M. Schilling et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," Appl. Phys. Lett. 49 (12), 22 September 1986	
<u>mm</u>	BN	Z. J. Sun et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998	
<u>mm</u>	BO	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990; pp. 198-202	
<u>mm</u>	BP	L. Torcheux et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem. Soc., Vol. 142, No. 6, June 1995	
Examiner Signature	<u>Thomas M. Dougherty</u>		Date Considered <u>3-2-05</u>

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		Art Unit	Not Yet Assigned 2839		
		Examiner Name	Not Yet Assigned T. Dougherty		
Sheet	3	of	3	Attorney Docket Number	019930-002840

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Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
DMJ		P. VanKessel et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704	
DMJ		Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998	
DMJ		Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller; Spring 2000	

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